

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q84452

Michel PUECH

Appln. No.: 10/516,455

Confirmation No.: 2876

Group Art Unit: 1792

Filed: December 3, 2004

Examiner: Allan W. OLSEN

For: METHOD AND DEVICE FOR SUBSTRATE ETCHING WITH VERY HIGH POWER  
INDUCTIVELY COUPLED PLASMA

**AMENDMENT UNDER 37 C.F.R. § 1.114(c)**

**MAIL STOP RCE**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated May 5, 2008, please amend the above-identified application as follows on the accompanying pages.

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